



PATENT  
Customer No. 22,852  
Attorney Docket No. 08038.0019-00000

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Amano

Application No.: 09/657,050

Filed: September 7, 2000

For: Device and Method for Plasma  
Processing

Group Art Unit: 1762

Examiner: M. L. Padgett

#8/10/02  
7/10/02  
RECEIVED  
JUL - 8 2002  
TECHNOLOGY CENTER 1100

Commissioner for Patents  
Washington, DC 20231

Sir:

AMENDMENT

In reply to the Office Action dated May 8, 2002, please amend the application as follows:

IN THE CLAIMS:

Please add new claim 9.

Please amend claims 1-3, 7 and 8 as follows:

1. (Amended) A plasma processing apparatus comprising:

a plurality of plasma processing units, each having a vacuum processing

chamber including a mounting stage for mounting a substrate with a fixed reference

point and a wave guide bent at an angle for introducing high frequency waves into said

FINNEGAN  
HENDERSON  
FARABOW  
GARRETT &  
DUNNER LLP

1300 I Street, NW  
Washington, DC 20005  
202.408.4000  
Fax 202.408.4400  
www.finnegan.com